

Claims

1. Device for drying disc-shaped substrates comprising
an elongated body (1) having a top surface, a bottom surface and a circumferential
surface,
5 comprising a hole in the top surface forming a channel (6)
which extends to a lower drainage part (B) of the elongated body and
is chamfered having a chamfer depth (L1) and a chamfer angle (α) forming an
edge between chamfer and top surface and forming a conical recess suitable for
resting a disc shaped substrate,
10 characterized in that the chamfer angle is more than 10° and less than 30° and
that the chamfer depth (L1) is more than 6 mm and less than 12 mm.
2. Device according to claim 1 characterized in that
the material used for the device comprises ceramic filled polyetheretherketone
(CFM PEEK).
- 15 3. Device according to any of claim 1 or claim 2, characterized in that
the edge between chamfer and top surface is rounded with a radius not more than
0.1 mm and not less than 1 mm.
4. Device according to any of claims 1 to 3, characterized in that
the diameter of the channel is not less than 0.5mm and not more than 3mm,
20 preferably not less than 0.8mm and not more than 1.2mm.
5. Device according to any of claims 1 to 4, characterized in that
the length of the channel (L2) is not less than 30 mm.